

What is claimed is:

1. A substrate testing device for testing a substrate by scanning of an electron beam across the substrate, comprising:

5 a testing unit for acquiring a tested result of the substrate by the scanning of the electron beam;

an alignment mark detecting unit for optically detecting an alignment mark on the substrate;

10 a substrate position calculating unit for calculating a substrate position within said substrate testing device from a position of said alignment mark; and

a position aligning unit for aligning a position of tested result with the calculated substrate position, said position aligning unit allocating the tested result to the substrate position.

15

2. The substrate testing device according to claim 1, wherein said position aligning unit aligns a defect result obtained by a defect test based on the tested result with the substrate position.

20

3. The substrate testing device according to claim 1, wherein said alignment mark detecting unit comprises an optical microscope or a CCD camera for picking up an image of the alignment mark on the substrate.

25

4. The substrate testing device according to claim 2, wherein said alignment mark detecting unit comprises an optical microscope or a CCD camera for picking up an image of the alignment mark on the substrate.

5

5. A substrate testing method for testing a substrate by scanning of an electron beam across the substrate within a substrate testing device, comprising:

acquiring a tested result of the substrate by the scanning  
10 of the electron beam;

optically detecting an alignment mark on the substrate;

calculating a substrate position within the substrate testing device from a position of the alignment mark;

aligning a position of tested result with the calculated  
15 substrate position; and

allocating the tested result to the substrate position.

6. The substrate testing method according to claim 5, wherein said position aligning step includes aligning a defect  
20 result obtained by a defect test based on the tested result with the substrate position.